



**MS AF**  
**Amendment Under 37 C.F.R. §1.116**  
**Expedited Processing**  
**Examining Group 2815**  
**PATENT**  
**3430-0131P**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

APPLICANT(S): HWANG, Kwang-Jo                      CONF.: 5562  
SERIAL NO.: 09/648,111                      GROUP: 2815  
FILED: August 25, 2000                      EXAMINER: BROCK II, P.  
FOR: METHOD OF PATTERNING A METAL LAYER IN A  
SEMICONDUCTOR DEVICE

**AMENDMENT UNDER 37 C.F.R. § 1.116**

**Box AF**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

December 20, 2005

Dear Sir:

In response to the final Office Action dated September 20, 2005, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

This reply includes Amendments to the Claims and Remarks.

OK to enter  
12/20/05